

INFORMATION DISCLOSURE CITATION

(Use several sheets if necessary)

Docket Number (Optional)

SC12592ZP

Application Number

Unknown

Applicant(s)

McNeill et al.

Filing Date

July 8, 2003

Group Art Unit

Unknown

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
X	1	U.S. 5,487,305	01/30/1996	Ristic et al.	73	514.32	07/12/1994
X	2	U.S. 5,594,171	01/14/1997	Ishida et al.	73	514.32	10/25/1995
X	3	U.S. 5,806,365	09/15/1998	Zunino et al.	73	514.16	04/30/1996
X	4	U.S. 5,939,633	08/17/1999	Judy	73	514.32	06/18/1997
X	5	U.S. 6,148,670	11/21/2000	Judy	73	514.32	06/10/1999
X	6	U.S. 6,223,598	05/01/2001	Judy	73	514.32	06/18/1997

FOREIGN PATENT DOCUMENTS

REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						YES	NO

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

X	1	J. Connelly, A. Kourepenis, T. Marinis, "MICROMECHANICAL SENSORS IN TACTICAL GN&C APPLICATIONS", The Charles Stark Draper Laboratory, Inc., Published by the American Institute of Aeronautics and Astronautics, Inc. (2000).
X	2	Giorgio Fontana, "High Performance Electrostatic Sensors and Actuators for LISA Proof Mass Control", arXiv:physics/0111006, Vol. 4 (Jan. 25, 2002)

EXAMINER

John Chapman

DATE CONSIDERED

7/29/04

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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*EXAMINER INITIAL	OTHER DOCUMENTS	(Including Author, Title, Date, Pertinent Pages, Etc.)
J	3	✓ Huikai Xie, Gary K. Fedder, "Vertical Comb-Finger Capacitive Actuation and Sensing For CMOS MEMS", Sensors and Actuators A95, 212-221 (2001)
J	4	✓ C. Byl, D. W. Howard, S. D. Collins and R. L. Smith, "MICROMACHINED, MULTI-AXIS, ACCELEROMETER with LIQUID PROOF MASS", Dept of Electrical & Computer Engineering University of California, Davis, California, Final Report 1998-99 for MICRO Project 98-145
J	5	✓ Harvey Weinberg, "Dual Axis, Low g, Fully Integrated Accelerometers", Analog Dialogue 33-1 (1999 Analog Devices)
J	6	✓ Michael Kraft, "Micromachined Inertial Sensors - Recent Developments at BSAC", pp. 1-37 (University of California - Berkeley) (presentation given at the New England American Vacuum Society Meeting in Burlington, MA, 15/06/1998)
J	7	✓ "Low Cost [±] 2 g/ [±] 10 g Dual Axis IMEMS® Accelerometers with Digital Output - ADXL202/ADXL210", Analog Devices, Inc. (C3037b-2, Rev. B, April, 1999).
J	8	"Low-Cost 2 g Dual-Axis Accelerometer with Duty Cycle Output - ADXL202E*", Analog Devices, Inc. (C02064-2.5-10, rev. A, 2000).
J	9	✓ Gary Li and Ampere A. Tseng, "Low Stress Packaging of a Micromachined Accelerometer", IEEE TRANSACTIONS ON ELECTRONICS PACKAGING MANUFACTURING, VOL. 24, NO. 1 (JANUARY 2001).

EXAMINER <div style="font-size: 1.2em; font-family: cursive;">John Chapman</div>	DATE CONSIDERED <div style="font-size: 1.2em; font-family: cursive;">7/29/04</div>
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